

The documentation and process conversion measures necessary to comply with this revision shall be completed by 18 June 2014.

INCH-POUND

MIL-PRF-19500/732C
 18 April 2014
 SUPERSEDING
 MIL-PRF-19500/732B
 23 April 2010

PERFORMANCE SPECIFICATION SHEET

* SEMICONDUCTOR DEVICE, FIELD EFFECT RADIATION HARDENED
 TRANSISTORS, P-CHANNEL, SILICON,
 TYPES 2N7519U3, 2N7519U3C, 2N7519T3, 2N7520U3, 2N7520U3C, AND 2N7520T3,
 JANTXVR, F AND JANSR, F

This specification is approved for use by all Departments and Agencies of the Department of Defense.

The requirements for acquiring the product described herein shall consist of this specification sheet and MIL-PRF-19500.

1. SCOPE

1.1 Scope. This specification covers the performance requirements for a P-channel, enhancement-mode, MOSFET, radiation hardened (total dose and single event effects (SEE)), power transistor. Two levels of product assurance are provided for each device type as specified in MIL-PRF-19500, with avalanche energy maximum rating (E_{AS}) and maximum avalanche current (I_{AS}). See 6.5 for JANHC and JANKC die versions.

1.2 Physical dimensions. See figure 1, TO-257AA (T3) and figure 2, SMD.5 TO-276AA (U3 or with ceramic lid, U3C).

1.3 Maximum ratings. Unless otherwise specified, T_A = +25°C.

| Type | P _T (1) T _C = +25°C | P _T T _A = +25°C | R _{θJC} (2) | V _{DS} | V _{DG} | V _{GS} | I _{D1} (3) (4) T _C = +25°C | I _{D2} (3) (4) T _C = +100°C | I _S | I _{DM} (5) | T _J and T _{STG} |
|---------------------|---|---|-------------------------|-----------------|-----------------|-----------------|---|--|----------------|------------------------|---|
| | <u>W</u> | <u>W</u> | <u>°C/W</u> | <u>V dc</u> | <u>V dc</u> | <u>V dc</u> | <u>A dc</u> | <u>A dc</u> | <u>A dc</u> | <u>A(pk)</u> | <u>°C</u> |
| 2N7519U3, 2N7519U3C | 75 | 1.56 | 1.67 | -30 | -30 | ±20 | -22 | -18 | -22 | -88 | -55 to |
| 2N7520U3, 2N7520U3C | 75 | 1.56 | 1.67 | -60 | -60 | ±20 | -21 | -13.3 | -21 | -84 | +150 |
| 2N7519T3 | 75 | 1.56 | 1.67 | -30 | -30 | ±20 | -20 | -18 | -20 | -80 | |
| 2N7520T3 | 75 | 1.56 | 1.67 | -60 | -60 | ±20 | -20 | -13 | -20 | -80 | |

- (1) Derate linearly 0.6 W/°C for T_C > +25°C.
- (2) See figure 3, thermal impedance curves.
- (3) The following formula derives the maximum theoretical I_D specs. I_D is limited by package and device construction to 20 A for TO-257AA and to 22 A for TO-276AA:

$$I_D = \sqrt{\frac{T_{JM} - T_C}{(R_{\theta JC}) \times (R_{DS(on)} \text{ at } T_{JM})}}$$

- (4) See figure 4, maximum drain current graph.
- (5) I_{DM} = 4 X I_{D1} as defined in note (3).

* Comments, suggestions, or questions on this document should be addressed to DLA Land and Maritime, ATTN: VAC, P.O. Box 3990, Columbus, OH 43218-3990, or emailed to Semiconductor@dla.mil. Since contact information can change, you may want to verify the currency of this address information using the ASSIST Online database at <https://assist.dla.mil>.

1.4 Primary electrical characteristics at T_C = +25°C.

| Type | Min V _{(BR)DSS} V _{GS} = 0 I _D = 1.0 mA dc | V _{GS(TH)1} V _{DS} ≥ V _{GS} I _D = 1.0 mA dc | | Max I _{DSS1} V _{GS} = 0 V _{DS} = 80 percent of rated V _{DS} | Max r _{DS(on)} (1) V _{GS} = 12 V dc | | E _{AS} at I _{D1} | I _{AS} |
|---------------------|---|--|------|---|--|--|---------------------------------------|-----------------|
| | | | | | T _J = +25°C at I _{D2} | T _J = +150°C at I _{D2} | | |
| | V dc | V dc | | μA dc | ohm | ohm | mJ | A |
| | | Min | Max | | | | | |
| 2N7519U3, 2N7519U3C | -30 | -2.0 | -4.0 | -10 | 0.070 | 0.091 | 152 | -22 |
| 2N7520U3, 2N7520U3C | -60 | -2.0 | -4.0 | -10 | 0.085 | 0.170 | 110 | -21 |
| 2N7519T3 | -30 | -2.0 | -4.0 | -10 | 0.072 | 0.094 | 200 | -20 |
| 2N7520T3 | -60 | -2.0 | -4.0 | -10 | 0.087 | 0.180 | 134 | -20 |

(1) Pulsed (see 4.5.1).

2. APPLICABLE DOCUMENTS

2.1 General. The documents listed in this section are specified in sections 3, 4, or 5 of this specification. This section does not include documents cited in other sections of this specification or recommended for additional information or as examples. While every effort has been made to ensure the completeness of this list, document users are cautioned that they must meet all specified requirements of documents cited in sections 3, 4, or 5 of this specification, whether or not they are listed.

2.2 Government documents.

2.2.1 Specifications, standards, and handbooks. The following specifications, standards, and handbooks form a part of this document to the extent specified herein. Unless otherwise specified, the issues of these documents are those cited in the solicitation or contract.

DEPARTMENT OF DEFENSE SPECIFICATIONS

[MIL-PRF-19500](#) – Semiconductor Devices, General Specification for.

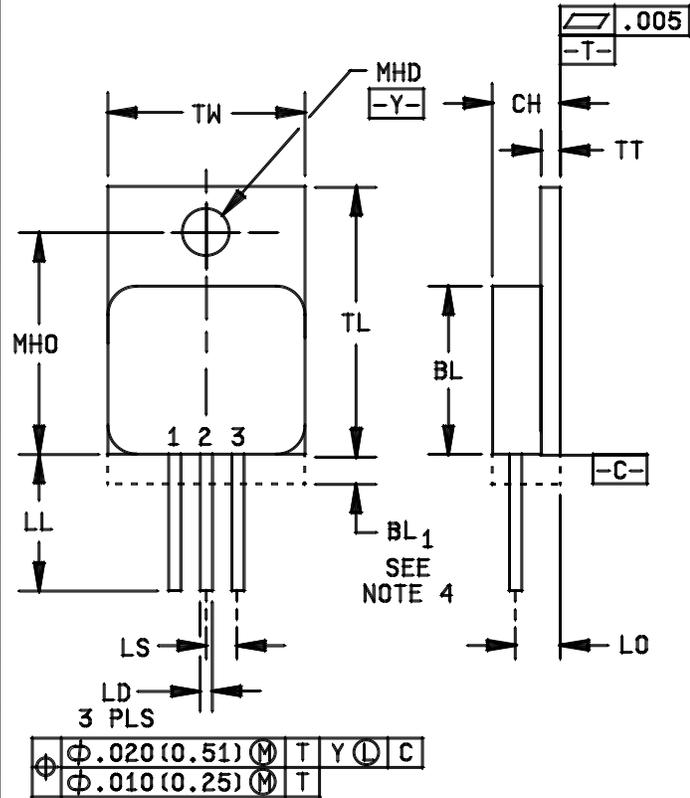
DEPARTMENT OF DEFENSE STANDARDS

[MIL-STD-750](#) – Test Methods for Semiconductor Devices.

* (Copies of these documents are available online at <http://quicksearch.dla.mil/>.)

2.3 Order of precedence. Unless otherwise noted herein or in the contract, in the event of a conflict between the text of this document and the references cited herein, the text of this document takes precedence. Nothing in this document, however, supersedes applicable laws and regulations unless a specific exemption has been obtained.

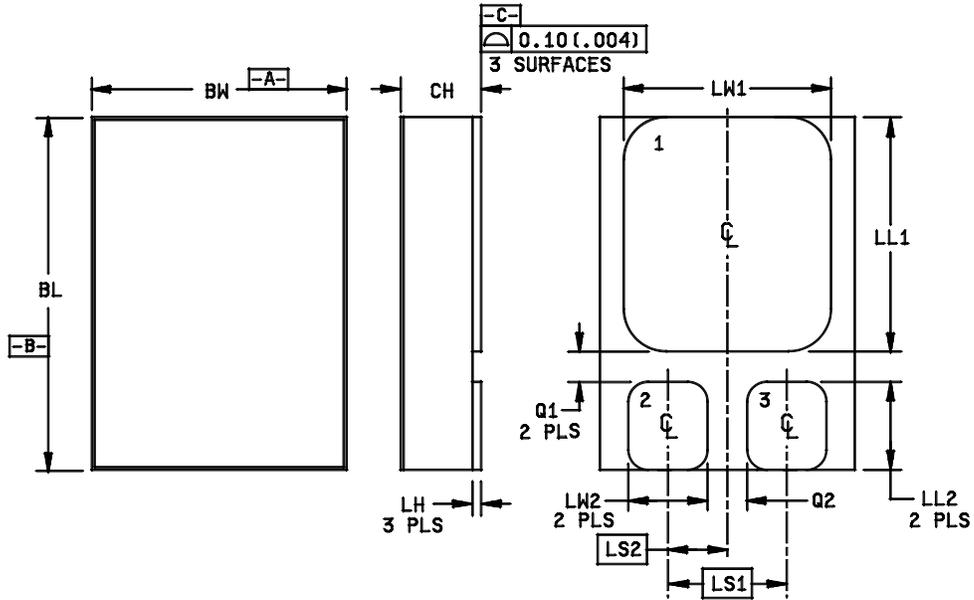
| Dimensions | | | | |
|-----------------|----------|------|-------------|-------|
| Ltr | Inches | | Millimeters | |
| | Min | Max | Min | Max |
| BL | .410 | .430 | 10.41 | 10.92 |
| BL ₁ | | .033 | | 0.84 |
| CH | .190 | .200 | 4.83 | 5.08 |
| LD | .025 | .035 | 0.64 | 0.89 |
| LL | .600 | .650 | 15.24 | 16.51 |
| LO | .120 BSC | | 3.05 BSC | |
| LS | .100 BSC | | 2.54 BSC | |
| MHD | .140 | .150 | 3.56 | 3.81 |
| MHO | .527 | .537 | 13.39 | 13.64 |
| TL | .645 | .665 | 16.38 | 16.89 |
| TT | .035 | .045 | 0.89 | 1.14 |
| TW | .410 | .420 | 10.41 | 10.67 |
| Term 1 | Drain | | | |
| Term 2 | Source | | | |
| Term 3 | Gate | | | |



NOTES:

1. Dimensions are in inches.
2. Millimeters are given for general information only.
3. All terminals are isolated from the case.
4. This area is for the lead feed-thru eyelets (configuration is optional, but will not extend beyond this zone).
5. In accordance with ASME Y14.5M, diameters are equivalent to ϕ x symbology.

FIGURE 1. Physical dimensions for TO-257AA (2N7519T3 and 2N7520T3).



| Ltr. | Dimensions | | | |
|--------------|------------|------|-------------|-------|
| | Inches | | Millimeters | |
| | Min | Max | Min | Max |
| BL | .395 | .405 | 10.03 | 10.29 |
| BW | .291 | .301 | 7.39 | 7.64 |
| CH (for U3) | | .124 | | 3.15 |
| CH (for U3C) | | .134 | | 3.40 |
| LH | .010 | .020 | 0.25 | 0.51 |
| LW1 | .281 | .291 | 7.14 | 7.39 |
| LW2 | .090 | .100 | 2.29 | 2.54 |
| LL1 | .220 | .230 | 5.59 | 5.84 |
| LL2 | .115 | .125 | 2.92 | 3.17 |
| LS1 | .150 BSC | | 3.81 BSC | |
| LS2 | .075 BSC | | 1.91 BSC | |
| Q1 | .030 | | 0.762 | |
| Q2 | .030 | | 0.762 | |
| TERM 1 | Drain | | | |
| TERM 2 | Gate | | | |
| TERM 3 | Source | | | |

NOTES:

1. Dimensions are in inches.
2. Millimeters are given for general information only.
3. In accordance with ASME Y14.5M, diameters are equivalent to ϕ x symbology.
4. Terminal 1 - Drain, Terminal 2 - Gate, Terminal 3 - Source.

FIGURE 2. Physical dimensions for SMD.5 TO-276AA (2N7519U3, 2N7519U3C, 2N7520U3, and 2N7520U3C).

3. REQUIREMENTS

3.1 General. The individual item requirements shall be as specified in MIL-PRF-19500 and as modified herein.

3.2 Qualification. Devices furnished under this specification shall be products that are manufactured by a manufacturer authorized by the qualifying activity for listing on the applicable qualified manufacturer's list (QML) before contract award (see 4.2 and 6.3).

3.3 Abbreviations, symbols, and definitions. Abbreviations, symbols, and definitions used herein shall be as specified in MIL-PRF-19500.

3.4 Interface and physical dimensions. The interface and physical dimensions shall be as specified in MIL-PRF-19500 and on figures 1 (T3, TO-257AA) and 2 (U3 and U3C, surface mount TO-276AA) herein.

3.4.1 Lead finish. Lead finish shall be solderable in accordance with MIL-PRF-19500, MIL-STD-750, and herein. Where a choice of lead finish is desired, it shall be specified in the acquisition document (see 6.2).

3.4.2 Internal construction. Multiple chip construction shall not be permitted to meet the requirements of this specification.

3.5 Electrostatic discharge protection. The devices covered by this specification require electrostatic discharge protection.

3.5.1 Handling. MOS devices shall be handled with certain precautions to avoid damage due to the accumulation of static charge. However, the following handling practices are recommended (see 3.5).

- a. Devices should be handled on benches with conductive handling devices.
- b. Ground test equipment, tools, and personnel handling devices.
- c. Do not handle devices by the leads.
- d. Store devices in conductive foam or carriers.
- e. Avoid use of plastic, rubber, or silk in MOS areas.
- f. Maintain relative humidity above 50 percent if practical.
- g. Care should be exercised during test and troubleshooting to apply not more than maximum rated voltage to any lead.
- h. Gate shall be terminated to source, $R \leq 100 \text{ k}\Omega$, whenever bias voltage is to be applied drain to source.

3.6 Electrical performance characteristics. Unless otherwise specified herein, the electrical performance characteristics are as specified in 1.3, 1.4, and table I herein.

3.7 Electrical test requirements. The electrical test requirements shall be as specified in table I.

3.8 Marking. Marking shall be in accordance with MIL-PRF-19500. At the option of the manufacturer, marking may be omitted from the body, but shall be retained on the initial container.

3.9 Workmanship. Semiconductor devices shall be processed in such a manner as to be uniform in quality and shall be free from other defects that will affect life, serviceability, or appearance.

4. VERIFICATION

4.1 Classification of inspections. The inspection requirements specified herein are classified as follows:

- a. Qualification inspection (see 4.2).
- b. Screening (see 4.3).
- c. Conformance inspection (see 4.4 and tables I and II).

4.2 Qualification inspection. Qualification inspection shall be in accordance with MIL-PRF-19500 and as specified herein.

4.2.1 Group E qualification. Group E inspection shall be performed for qualification or re-qualification only. In case qualification was awarded to a prior revision of the specification sheet that did not request the performance of [table III](#) tests, the tests specified in [table III](#) herein that were not performed in the prior revision shall be performed on the first inspection lot of this revision to maintain qualification.

4.2.2 SEE. Design capability shall be tested on the initial qualification and thereafter whenever a major die design or process change is introduced. See the design safe operation area figures herein. Electrical measurements (end-points) shall be in accordance with [table III](#) herein.

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* 4.3 Screening (JANS and JANTXV levels only). Screening shall be in accordance with table E-IV of MIL-PRF-19500 and as specified herein. The following measurements shall be made in accordance with table I herein. Devices that exceed the limits of table I herein shall not be acceptable.

| Screen (see table E-IV of MIL-PRF-19500) (1) (2) | Measurement | |
|---|--|---|
| | JANS level | JANTXV level |
| (3) | Gate stress test (see 4.3.1) | Gate stress test (see 4.3.1) |
| (3) | Method 3470 of MIL-STD-750, E _{AS} (see 4.3.2) | Method 3470 of MIL-STD-750, E _{AS} (see 4.3.2) |
| (3) 3c | Method 3161 of MIL-STD-750, thermal impedance (see 4.3.3) | Method 3161 of MIL-STD-750, thermal impedance (see 4.3.3) |
| (1) 9 | Subgroup 2 of table I herein; I _{GSSF1} , I _{GSSR1} , I _{DSS1} | Not applicable |
| 10 | Method 1042 of MIL-STD-750, test condition B | Method 1042 of MIL-STD-750, test condition B |
| 11 | Subgroup 2 of table I herein; I _{GSSF1} , I _{GSSR1} , I _{DSS1} , r _{DS(on)1} , V _{GS(TH)1} . Δ I _{GSSF1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. Δ I _{GSSR1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. Δ I _{DSS1} = ±10 μA dc or ±100 percent of initial value, whichever is greater. | Subgroup 2 of table I herein; I _{GSSF1} , I _{GSSR1} , I _{DSS1} , r _{DS(on)1} , V _{GS(TH)1} |
| 12 | Method 1042 of MIL-STD-750, test condition A | Method 1042 of MIL-STD-750, test condition A |
| 13 | Subgroups 2 and 3 of table I herein; Δ I _{GSSF1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. Δ I _{GSSR1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. Δ I _{DSS1} = ±10 μA dc or ±100 percent of initial value, whichever is greater. Δ r _{DS(on)1} = ± 20 percent of initial value. Δ V _{GS(TH)1} = ±20 percent of initial value. | Subgroups 2 and 3 of table I herein; Δ I _{GSSF1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. Δ I _{GSSR1} = ±20 nA dc or ±100 percent of initial value, whichever is greater. Δ I _{DSS1} = ±10 μA dc or ±100 percent of initial value, whichever is greater. Δ r _{DS(on)1} = ±20 percent of initial value. Δ V _{GS(TH)1} = ±20 percent of initial value. |
| 17 | For TO-257 packages: Method 1081 of MIL-STD-750 (see 4.3.4), Endpoints: Subgroup 2 of table I herein. | For TO-257 packages: Method 1081 of MIL-STD-750 (see 4.3.4), Endpoints: Subgroup 2 of table I herein. |

- (1) At the end of the test program, I_{GSSF1}, I_{GSSR1}, and I_{DSS1} are measured.
- (2) An out-of-family program to characterize I_{GSSF1}, I_{GSSR1}, I_{DSS1}, and V_{GS(th)1} shall be invoked.
- (3) Shall be performed anytime after temperature cycling, screen 3a; JANTX and JANTXV levels do not need to be repeated in screening requirements.

4.3.1 Gate stress test. Apply $V_{GS} = -24$ V minimum for $t = 250$ μ s minimum.

4.3.2 Single pulse avalanche energy (E_{AS}).

- a. Peak current (I_{AS}) $I_{AS(max)}$.
- b. Peak gate voltage (V_{GS}) 12 V.
- c. Gate to source resistor (R_{GS}) $25\Omega \leq R_{GS} \leq 200\Omega$.
- d. Initial case temperature (T_C) $+25^\circ\text{C} +10^\circ\text{C}, -5^\circ\text{C}$.
- e. Inductance (L)..... $\left[\frac{2E_{AS}}{(I_{DI})^2} \right] \left[\frac{(V_{BR} - V_{DD})}{V_{BR}} \right] \text{mH minimum.}$
- f. Number of pulses to be applied 1 pulse minimum.
- g. Supply voltage (V_{DD}) 25 V.

4.3.3 Thermal impedance. The thermal impedance measurements shall be performed in accordance with method 3161 of MIL-STD-750 using the guidelines in that method for determining I_M , I_H , t_H , t_{SW} , (and V_H where appropriate). Measurement delay time (t_{MD}) = 70 μ s max. See [table III](#), group E, subgroup 4 herein.

* 4.3.4 Dielectric withstanding voltage.

- a. Magnitude of test voltage.....800 V dc.
- b. Duration of application of test voltage.....15 seconds (min).
- c. Points of application of test voltage.....All leads to case (bunch connection).
- d. Method of connection.....Mechanical.
- e. Kilovolt-ampere rating of high voltage source.....1,200 V/1.0 mA (min).
- f. Maximum leakage current.....1.0 mA.
- g. Voltage ramp up time.....500 V/second

4.4 Conformance inspection. Conformance inspection shall be in accordance with MIL-PRF-19500, and as specified herein.

4.4.1 Group A inspection. Group A inspection shall be conducted in accordance with table E-V of MIL-PRF-19500. End-point electrical measurements shall be in accordance with [table I](#), subgroup 2 herein.

4.4.2 Group B inspection. Group B inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-VIA (JANS) and table E-VIB (JANTXV) of MIL-PRF-19500, and herein. Electrical measurements (end-points) shall be in accordance with [table I](#), subgroup 2 herein.

* 4.4.2.1 Group B inspection, table E-VIA (JANS) of MIL-PRF-19500.

| <u>Subgroup</u> | <u>Method</u> | <u>Inspection</u> |
|-----------------|---------------|---|
| B3 | 1051 | Test condition G, 100 cycles. |
| B3 | 2077 | Scanning electron microscope (SEM) qualification may be performed anytime prior to lot formation. |
| * B4 | 1042 | Condition D. No heat sink nor forced-air cooling on the device shall be permitted during the on cycle. $t_{on} = 30$ seconds minimum. |
| B5 | 1042 | Test condition B, $V_{GS} = \text{rated}$; $T_A = +175^\circ\text{C}$; $t = 24$ hours. |
| B5 | 1042 | Test condition A, $V_{DS} = \text{rated}$; $T_A = +175^\circ\text{C}$; $t = 120$ hours. |
| B5 | 2037 | Bond strength, test condition D. |

* 4.4.2.2 Group B inspection, table E-VIB (JANTXV) of MIL-PRF-19500.

| <u>Subgroup</u> | <u>Method</u> | <u>Inspection</u> |
|-----------------|---------------|--|
| B2 | 1051 | Test condition G, 25 cycles. (45 total, including 20 cycles performed in screening). |
| * B3 | 1042 | Test condition D. No heat sink nor forced-air cooling on the device shall be permitted during the on cycle. $t_{on} = 30$ seconds minimum. |
| B5 and B6 | | Not applicable. |

* 4.4.3 Group C inspection. Group C inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-VII of MIL-PRF-19500 and as follows. Electrical measurements (end-points) shall be in accordance with [table I](#), subgroup 2 herein.

| <u>Subgroup</u> | <u>Method</u> | <u>Inspection</u> |
|-----------------|---------------|--|
| C2 | 2036 | Test condition A, weight = 10 lbs (4.54 Kg), $t = 10$ s (applicable to TO-257AA only). |
| C5 | 3161 | See 4.3.3 , $R_{\theta JC(\text{max})} = 1.67^\circ\text{C/W}$. |
| * C6 | 1042 | Test condition D. No heat sink nor forced-air cooling on the device shall be permitted during the on cycle. $t_{on} = 30$ seconds minimum. |

4.4.4 Group D inspection. Group D inspection shall be conducted in accordance with table E-VIII of MIL-PRF-19500 and [table II](#) herein.

4.4.5 Group E inspection. Group E inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-IX of MIL-PRF-19500 and as specified herein. Electrical measurements (end-points) shall be in accordance with [table I](#), subgroup 2 herein.

4.5 Methods of inspection. Methods of inspection shall be as specified in the appropriate tables and as follows.

4.5.1 Pulse measurements. Conditions for pulse measurement shall be as specified in section 4 of MIL-STD-750.

TABLE I. Group A inspection.

| Inspection <u>1/</u> | MIL-STD-750 | | Symbol | Limits | | Unit |
|--|-------------|--|-----------------|--------|----------------------------------|--|
| | Method | Conditions | | Min | Max | |
| <u>Subgroup 1</u> | | | | | | |
| Visual and mechanical inspection | 2071 | | | | | |
| <u>Subgroup 2</u> | | | | | | |
| Thermal impedance <u>2/</u> | 3161 | See 4.3.3 | $Z_{\theta JC}$ | | | $^{\circ}C/W$ |
| Breakdown voltage, drain to source | 3407 | $V_{GS} = 0$ V dc, $I_D = -1$ mA dc, bias condition C | $V_{(BR)DSS}$ | | | |
| 2N7519U3, 2N7519T3 2N7519U3C | | | | -30 | | V dc |
| 2N7520U3, 2N7520T3 2N7520U3C | | | | -60 | | V dc |
| Gate to source voltage (threshold) | 3403 | $V_{DS} \geq V_{GS}$, $I_D = -1$ mA dc | $V_{GS(TH)1}$ | -2.0 | -4.0 | V dc |
| Gate reverse current | 3411 | $V_{GS} = +20$ V dc, bias condition C, $V_{DS} = 0$ | I_{GSSF1} | | +100 | nA dc |
| Gate reverse current | 3411 | $V_{GS} = -20$ V dc, bias condition C, $V_{DS} = 0$ | I_{GSSR1} | | -100 | nA dc |
| Drain current | 3413 | $V_{GS} = 0$ V dc, bias condition C, $V_{DS} = 80$ percent of rated V_{DS} | I_{DSS1} | | -10 | μA dc |
| Static drain to source on-state resistance | 3421 | $V_{GS} = -12$ V dc, condition A, pulsed (see 4.5.1), $I_D = I_{D2}$ | $r_{DS(on)1}$ | | | |
| 2N7519U3, 2N7519U3C 2N7520U3, 2N7520U3C 2N7519T3 2N7520T3 | | | | | 0.070 0.085 0.072 0.087 | Ω Ω Ω Ω |
| Forward voltage | 4011 | Pulsed (see 4.5.1), $I_D = I_{D1}$, $V_{GS} = 0$ V dc | V_{SD} | | -5.0 | V |
| <u>Subgroup 3</u> | | | | | | |
| High temperature operation: | | $T_C = T_J = +125^{\circ}C$ | | | | |
| Gate reverse current | 3411 | $V_{GS} = -20$ V dc and $+20$ V dc, bias condition C, $V_{DS} = 0$ | I_{GSS2} | | ± 200 | nA dc |
| Drain current | 3413 | $V_{GS} = 0$ V dc, bias condition C, $V_{DS} = 80$ percent of rated V_{DS} | I_{DSS2} | | -25 | μA dc |

See footnotes at end of table.

TABLE I. Group A inspection - Continued.

| Inspection 1/ | MIL-STD-750 | | Symbol | Limits | | Unit |
|--|-------------|--|---------------|----------|----------------------------------|--|
| | Method | Conditions | | Min | Max | |
| <u>Subgroup 3</u> - Continued | | | | | | |
| Static drain to source on-state resistance 2N7519U3, 2N7519U3C 2N7520U3, 2N7520U3C 2N7519T3 2N7520T3 | 3421 | $V_{GS} = -12$ V dc, pulsed (see 4.5.1), $I_D = I_{D2}$ | $r_{DS(on)3}$ | | 0.084 0.136 0.086 0.139 | Ω Ω Ω Ω |
| Gate to source voltage (threshold) | 3403 | $V_{DS} \geq V_{GS}$, $I_D = -1$ mA dc | V GS(TH)2 | -1.0 | | V dc |
| Low temperature operation: | | $T_C = T_J = -55^\circ\text{C}$ | | | | |
| Gate to source voltage (threshold) | 3403 | $V_{DS} \geq V_{GS}$, $I_b = -1$ mA dc | V GS(TH)3 | | -5.0 | V dc |
| <u>Subgroup 4</u> | | | | | | |
| Forward transconductance 2N7519U3, 2N7519U3C, 2N7519T3 2N7520U3, 2N7520U3C, 2N7520T3 | 3475 | $I_D = \text{rated } I_{D2}$, $V_{DD} = -15$ V (see 4.5.1) | gFS | 12 10 | | S S |
| Switching time test | 3472 | $I_D = \text{rated } I_{D1}$, $V_{GS} = -12$ V dc, $R_G = 7.5 \Omega$, $V_{DD} = 50$ percent of rated V_{DS} | | | | |
| Turn-on delay time | | | $t_{d(on)}$ | | 25 | ns |
| Rise-time | | | t_r | | 100 | ns |
| 2N7519U3, 2N7519U3C, 2N7519T3 2N7520U3, 2N7520U3C, 2N7520T3 | | | | | 65 | ns |
| Turn-off delay time | | | $t_{d(off)}$ | | 50 | ns |
| 2N7519U3, 2N7519U3C, 2N7519T3 2N7520U3, 2N7520U3C, 2N7520T3 | | | | | 75 | ns |
| Fall time | | | t_f | | 70 | ns |
| 2N7519U3, 2N7519U3C, 2N7519T3 2N7520U3, 2N7520U3C, 2N7520T3 | | | | | 50 | ns |

See footnotes at end of table.

TABLE II. Group D inspection.

| Inspection 1/ 2/ 3/ | | | Symbol | Pre-irradiation limits | | Post-irradiation limits | | Post-irradiation limits | | Unit |
|--|--------|--|---------------|------------------------|------|-------------------------|------|-------------------------|------|------------------|
| | Method | Conditions | | R, F | | R | | F | | |
| | | | | Min | Max | Min | Max | Min | Max | |
| <u>Subgroup 1</u> | | | | | | | | | | |
| Not applicable | | | | | | | | | | |
| <u>Subgroup 2</u> | | $T_C = +25^\circ\text{C}$ | | | | | | | | |
| Steady-state total dose irradiation (V_{GS} bias) 4/ | 1019 | $V_{GS} = -12\text{V}$ $V_{DS} = 0$ | | | | | | | | |
| Steady-state total dose irradiation (V_{DS} bias) 4/ | 1019 | $V_{GS} = 0$ $V_{DS} = 80$ percent of rated V_{DS} (pre-irradiation) | | | | | | | | |
| End-point electricals: | | | | | | | | | | |
| Breakdown voltage, drain to source | 3407 | $V_{GS} = 0$ $I_D = -1$ mA bias condition C | $V_{(BR)DSS}$ | | | | | | | |
| 2N7519U3, 2N7519U3C, 2N7519T3 | | | | -30 | | -30 | | -30 | | V dc |
| 2N7520U3, 2N7520U3C, 2N7520T3 | | | | -60 | | -60 | | -60 | | V dc |
| Gate to source voltage (threshold) | 3403 | $V_{DS} \geq V_{GS}$ | $V_{GS(th)1}$ | -2.0 | -4.0 | -2.0 | -4.0 | -2.0 | -5.0 | V dc |
| Gate reverse current | 3411 | $V_{GS} = -20$ V $V_{DS} = 0$ bias condition C | I_{GSSR1} | | -100 | | -100 | | -100 | nA dc |
| Gate forward current | 3411 | $V_{GS} = 20$ V $V_{DS} = 0$ bias condition C | I_{GSSF1} | | 100 | | 100 | | 100 | nA dc |
| Drain current | 3413 | $V_{GS} = 0$ bias condition C $V_{DS} = 80$ percent of rated V_{DS} (pre-irradiation) | I_{DSS1} | | -10 | | -10 | | -10 | μA dc |

See footnotes at end of table.

TABLE II. Group D inspection - Continued.

| Inspection <u>1/</u> <u>2/</u> <u>3/</u> | MIL-STD-750 | | Symbol | Pre-irradiation limits | | Post-irradiation limits | | Post-irradiation limits | | Unit |
|---|-------------|--|---------------|------------------------|-------|-------------------------|-------|-------------------------|-------|------|
| | Method | Conditions | | R, F | | R | | F | | |
| | | | | Min | Max | Min | Max | Min | Max | |
| Static drain to source on-state voltage 2N7519U3 2N7519U3C 2N7520U3 2N7520U3C 2N7519T3 2N7520T3 | 3405 | $V_{GS} = -12$ V condition A pulsed (see 4.5.1) $I_D = I_{D2}$ | $V_{DS(on)1}$ | | | | | | | |
| | | | | | 1.296 | | 1.296 | | 1.296 | V dc |
| | | | | | 1.157 | | 1.157 | | 1.157 | V dc |
| | | | | | 1.296 | | 1.296 | | 1.296 | V dc |
| | | | | | 1.131 | | 1.131 | | 1.131 | V dc |
| Forward voltage source to drain diode | 4011 | $V_{GS} = 0$ $I_D = I_{D1}$ | V_{SD} | | -5.0 | | -5.0 | | -5.0 | V dc |

1/ For sampling plan, see MIL-PRF-19500.

2/ Group D qualification may be performed anytime prior to lot formation. Wafers qualified to these group D QCI requirements may be used for any other specification sheet utilizing the same die design.

3/ At the manufacturer's option, group D samples need not be subjected to the screening tests, and may be assembled in its qualified package, or in any qualified package, that the manufacturer has data to correlate the performance to the designated package.

4/ Separate samples shall be pulled for each bias.

* TABLE III. Group E inspection (all quality levels) for qualification or re-qualification only.

| Inspection | MIL-STD-750 | | Qualification and large lot quality conformance inspection |
|--|-------------|--|--|
| | Method | Conditions | |
| <u>Subgroup 1</u> | | | 45 devices c = 0 |
| Temperature cycling | 1051 | Test condition G, 500 cycles | |
| Hermetic seal | 1071 | As applicable | |
| Fine leak | | | |
| Gross leak | | | |
| Electrical measurements | | See table I , subgroup 2 | |
| <u>Subgroup 2 1/</u> | | | 45 devices c = 0 |
| Steady-state reverse bias | 1042 | Condition A, 1,000 hours | |
| Electrical measurements | | See table I , subgroup 2 | |
| Steady-state gate bias | 1042 | Condition B, 1,000 hours | |
| Electrical measurements | | See table I , subgroup 2 | |
| <u>Subgroup 4</u> | | | Sample size N/A |
| Thermal impedance curves | | See MIL-PRF-19500 | |
| <u>Subgroup 10</u> | | | 22 devices c = 0 |
| Commutating diode for safe operating area test procedure for measuring dv/dt during reverse recovery of power MOSFET transistors or insulated gate bipolar transistors | 3476 | Test conditions shall be derived by the manufacturer | |

1/ A separate sample for each test shall be pulled.

2/ Group E qualification of SEE testing may be performed prior to lot formation. Qualification may be extended to other specification sheets utilizing the same structurally identical die design.

3/ The sampling plan applies to each bias condition.

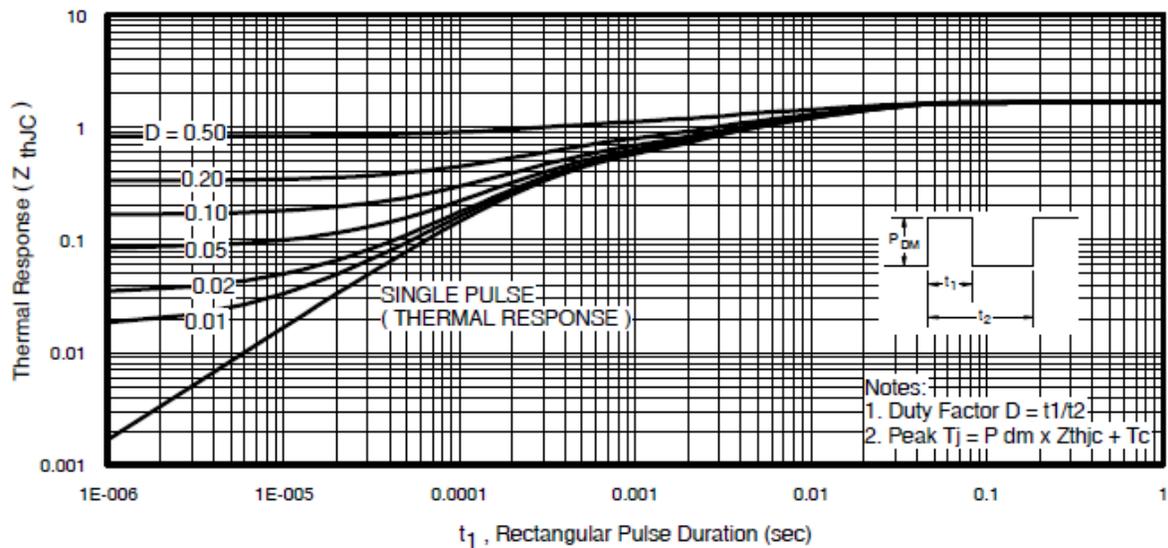


FIGURE 3. Thermal impedance curves.

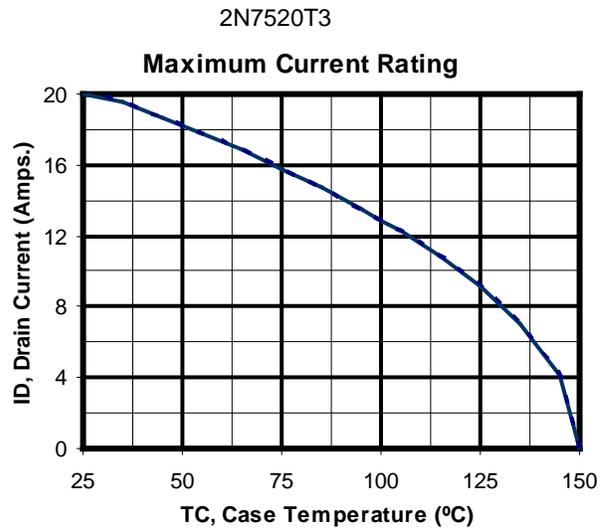
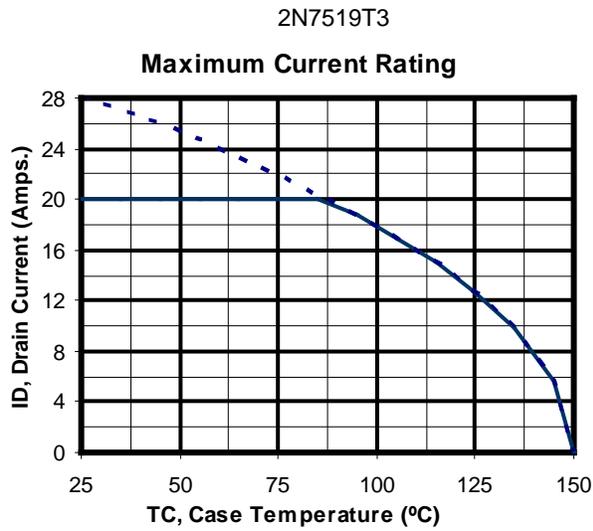
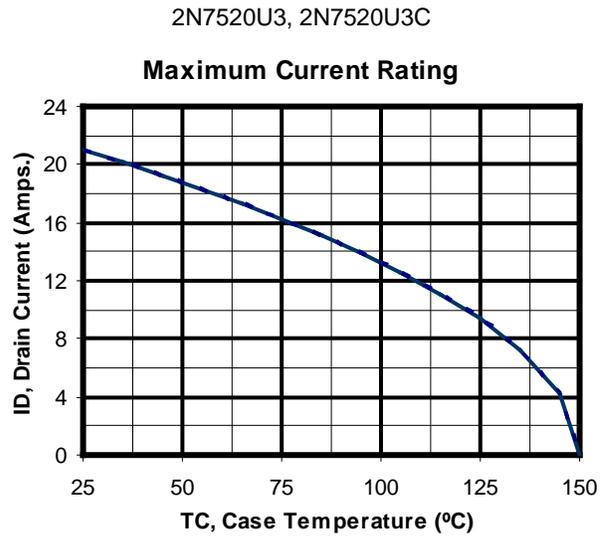
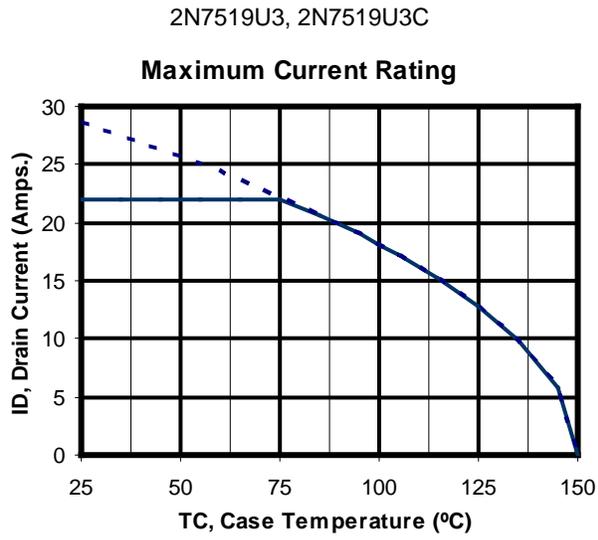


FIGURE 4. Maximum drain current versus case temperature graphs.

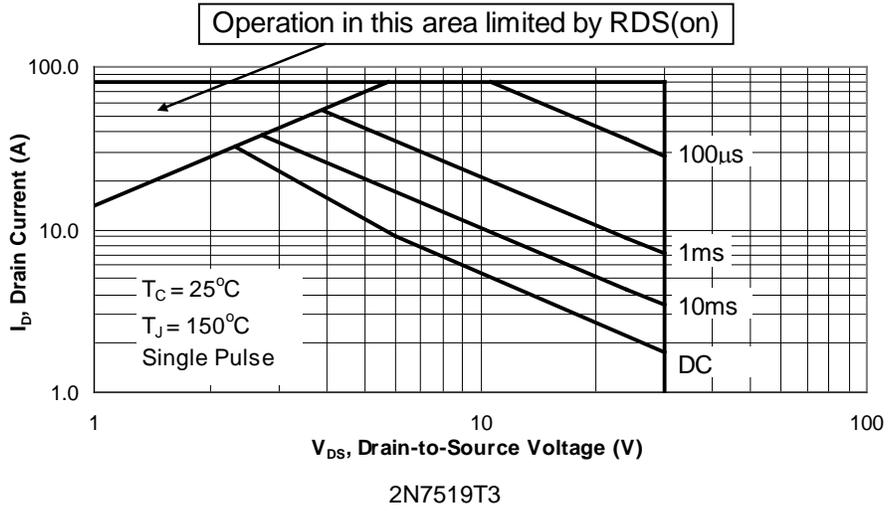
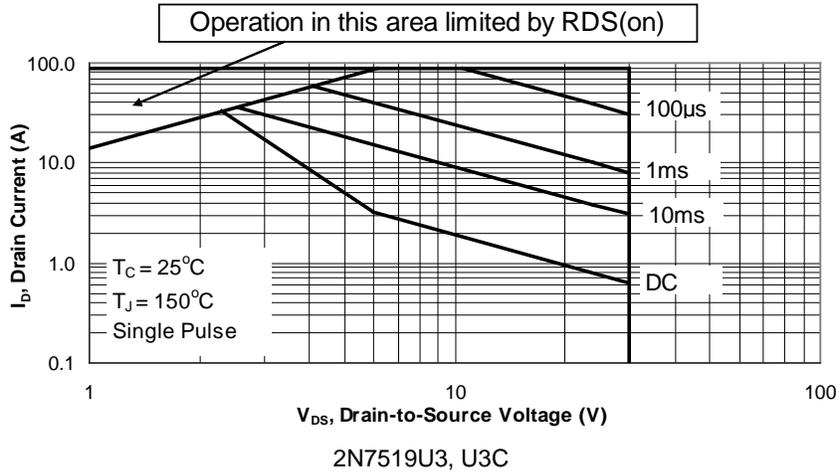
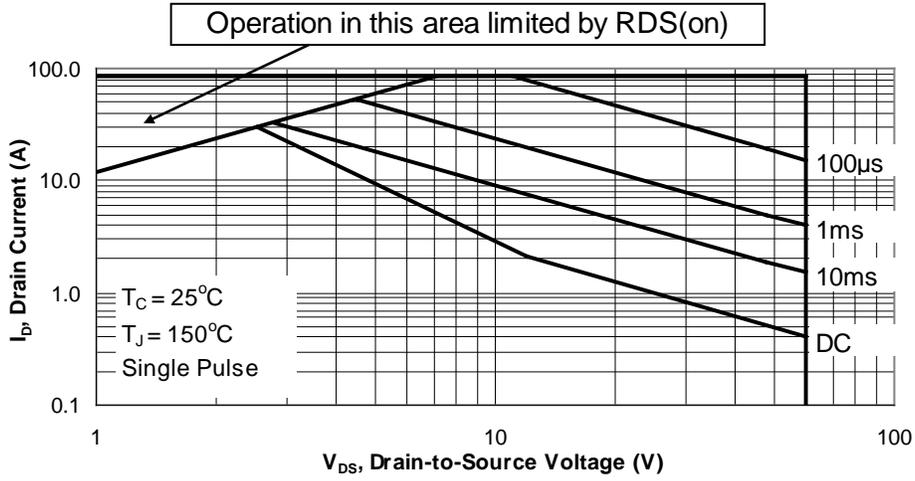
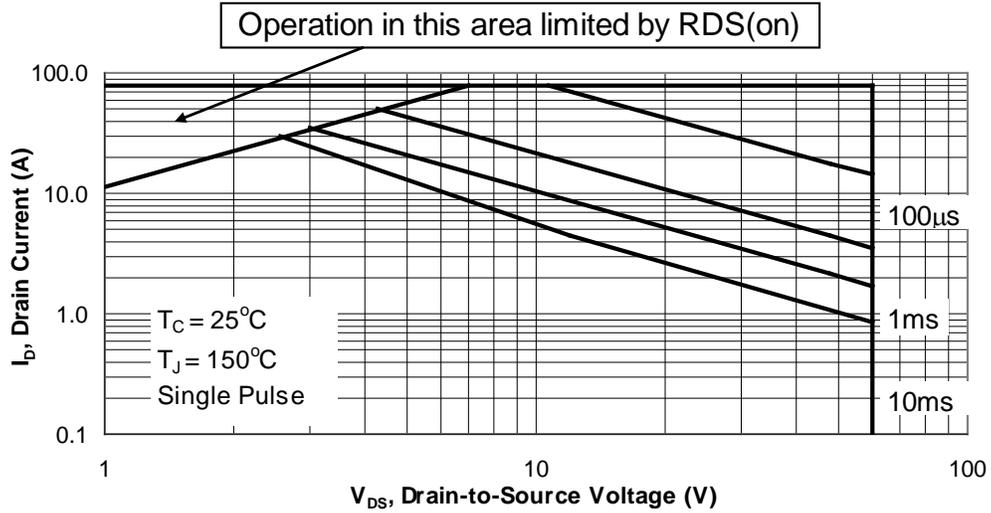


FIGURE 5. Safe operating area graph.



2N7520U3 an U3C



2N7520T3

FIGURE 5. Safe operating area graph. - Continued.

5. PACKAGING

5.1 Packaging. For acquisition purposes, the packaging requirements shall be as specified in the contract or order (see 6.2). When packaging of materiel is to be performed by DoD or in-house contractor personnel, these personnel need to contact the responsible packaging activity to ascertain packaging requirements. Packaging requirements are maintained by the Inventory Control Point's packaging activities within the Military Service or Defense Agency, or within the Military Service's system commands. Packaging data retrieval is available from the managing Military Department's or Defense Agency's automated packaging files, CD-ROM products, or by contacting the responsible packaging activity.

6. NOTES

(This section contains information of a general or explanatory nature that may be helpful, but is not mandatory. The notes specified in MIL-PRF-19500 are applicable to this specification.)

6.1 Intended use. Semiconductors conforming to this specification are intended for original equipment design applications and logistic support of existing equipment.

- * 6.2 Acquisition requirements. Acquisition documents should specify the following:
- a. Title, number, and date of this specification.
 - b. Packaging requirements (see 5.1).
 - c. Lead finish (see 3.4.1).
 - d. Product assurance level and type designator.
 - e. For acquisition of RHA designated devices, [table II](#), subgroup 1 testing of group D herein is optional. If subgroup 1 is desired, it should be specified in the contract.
 - f. If specific SEE characterization conditions are desired (see section 6.6 and [table IV](#)), manufacturer's cage code should be specified in the contract or order.
 - g. If SEE testing data is desired, it should be specified in the contract or order.
- * 6.3 Qualification. With respect to products requiring qualification, awards will be made only for products which are, at the time of award of contract, qualified for inclusion in Qualified Manufacturers List (QML 19500) whether or not such products have actually been so listed by that date. The attention of the contractors is called to these requirements, and manufacturers are urged to arrange to have the products that they propose to offer to the Federal Government tested for qualification in order that they may be eligible to be awarded contracts or orders for the products covered by this specification. Information pertaining to qualification of products may be obtained from DLA Land and Maritime, ATTN: VQE, P.O. Box 3990, Columbus, OH 43218-3990 or e-mail vqe.chief@dla.mil. An online listing of products qualified to this specification may be found in the Qualified Products Database (QPD) at <https://assist.dla.mil>.

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6.4 Substitution information. Devices covered by this specification are substitutable for the manufacturer's and user's Part or Identifying Number (PIN). This information in no way implies that manufacturer's PIN's are suitable for the military PIN.

| Preferred types (military PIN) | Commercial PIN | | |
|-----------------------------------|----------------|--------------------|--|
| | TO-257AA | TO-276AA (SMD-0.5) | TO-276AA (SMD-0.5) with ceramic lid |
| 2N7519U3 | | IRHNJ597Z30 | |
| 2N7520U3 | | IRHNJ597034 | |
| 2N7519T3 | IRHYS597Z30CM | | |
| 2N7520T3 | IRHYS597034CM | | |
| 2N7519U3C | | | IRHNJC597Z30 |
| 2N7520U3C | | | IRHNJC597034 |

6.5 JANC die versions. The JANHC and JANKC die versions of these devices are covered under specification sheet [MIL-PRF-19500/741](#).

* 6.6 Application data.

* 6.6.1 Manufacturer specific irradiation data. Each manufacturer qualified to this slash sheet has characterized its devices to the requirements of MIL-STD-750 method 1080 and as specified herein. Since each manufacturer's characterization conditions can be different and can vary by the version of method 1080 qualified to, the MIL-STD-750 method 1080 revision version date and conditions used by each manufacturer for characterization have been listed here (see [table IV](#)) for information only. SEE conditions and figures listed in section 6 are current as of the date of this specification sheet, please contact the manufacturer for the most recent conditions.

* TABLE IV. Manufacturers characterization conditions.

| Manufacturers CAGE | Inspection | MIL-STD-750 | | Sample plan |
|--|--|--|--|----------------|
| | | Method | Conditions | |
| 69210 (Applicable to devices with a date code of September 2009 and older) | SEE <u>1/</u> | 1080 | See MIL-STD-750 method 1080 | 3 devices |
| | Electrical measurements | | I_{GSSF1} , I_{GSSR1} , and I_{DSS1} in accordance with table I , subgroup 2 | |
| | SEE irradiation: | | Fluence = $3E5 \pm 20$ percent ions/cm ² , flux = $2E3$ to $2E4$ ions/cm ² /sec, temperature = $25 \pm 5^\circ C$ | |
| | 2N7519U3, 2N7519U3C, and 2N7519T3 | | In situ bias conditions: $V_{DS} = -30$ V and $V_{GS} = 20$ V, (nominal 3.42 MeV/nucleon at Texas A & M Cyclotron) | |
| | 2N7520U3, 2N7520U3C, and 2N7520T3 | | In situ bias conditions: $V_{DS} = -60$ V and $V_{GS} = 20$ V, (nominal 3.86 MeV/nucleon at Brookhaven National Lab Accelerator) | |
| | 2N7519U3, 2N7519U3C, and 2N7519T3 | | Surface LET = 61 MeV-cm ² /mg $\pm 5\%$, range = $31 \mu m$ $\pm 10\%$, energy = 330 MeV $\pm 7.5\%$ | |
| 2N7520U3, 2N7520U3C, and 2N7520T3 | In situ bias conditions: $V_{DS} = -30$ V and $V_{GS} = 15$ V, $V_{DS} = -25$ V and $V_{GS} = 20$ V, (nominal 2.53 MeV/nucleon at Texas A & M Cyclotron) | | | |
| | 2N7520U3, 2N7520U3C, and 2N7520T3 | In situ bias conditions: $V_{DS} = -60$ V and $V_{GS} = 10$ V, $V_{DS} = -45$ V and $V_{GS} = 15$ V, $V_{DS} = -25$ V and $V_{GS} = 20$ V, (nominal 2.92 MeV/nucleon at Brookhaven National Lab Accelerator) | | |
| | | Surface LET = 84 MeV-cm ² /mg $\pm 5\%$, range = $28 \mu m$ $\pm 7.5\%$, energy = 350 MeV $\pm 10\%$ | | |

See footnotes at end of table.

* TABLE IV. Manufacturers characterization conditions (continued).

| Manufacturers CAGE | Inspection | MIL-STD-750 | | Sample plan |
|--|---|-------------|--|-------------|
| | | Method | Conditions | |
| 69210 (Applicable to devices with a date code of September 2009 and older) | SEE 1/ | 1080 | See MIL-STD-750 method 1080 | 3 devices |
| | Electrical measurements | | I_{GSS1} and I_{DSS1} in accordance with table I , subgroup 2 | |
| | SEE irradiation: | | Fluence = $3E5 \pm 20$ percent ions/cm ² , flux = $2E3$ to $2E4$ ions/cm ² /sec, temperature = $25 \pm 5^\circ C$ | |
| | 2N7519U3, 2N7519U3C, and 2N7519T3 | | In situ bias conditions: $V_{DS} = -30$ V and $V_{GS} = 10$ V, $V_{DS} = -25$ V and $V_{GS} = 15$ V, (nominal 1.74 MeV/nucleon at Texas A & M Cyclotron) | |
| 2N7520U3, 2N7520U3C, and 2N7520T3 | In situ bias conditions: $V_{DS} = -60$ V and $V_{GS} = 10$ V, (nominal 1.98 MeV/nucleon at Brookhaven National Lab Accelerator) | | | |
| | Electrical measurements | | I_{GSS1} and I_{DSS1} in accordance with table I , subgroup 2 | |
| <div style="border: 1px solid black; padding: 5px; width: fit-content; margin: auto;"> Upon qualification, all manufacturers will provide the verification test conditions to be added to this table. </div> | | | | |

1/ I_{GSSF1} , I_{GSSR1} , and I_{DSS1} was examined before and following SEE irradiation to determine acceptability for each bias condition. Other test conditions in accordance with [table I](#), subgroup 2, may be performed at the manufacturer's option.

6.7 Changes from previous issue. The margins of this specification are marked with asterisks to indicate where changes from the previous issue were made. This was done as a convenience only and the Government assumes no liability whatsoever for any inaccuracies in these notations. Bidders and contractors are cautioned to evaluate the requirements of this document based on the entire content irrespective of the marginal notations and relationship to the previous issue.

Custodians:
Army - CR
Navy - EC
Air Force - 85
NASA - NA
DLA - CC

Preparing activity:
DLA - CC

(Project 5961-2014-046)

Review activity:
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